

# SVT Upgrade Status

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*Tim Nelson - November 27, 2017*

# Three Significant Subprojects

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*new sensors*

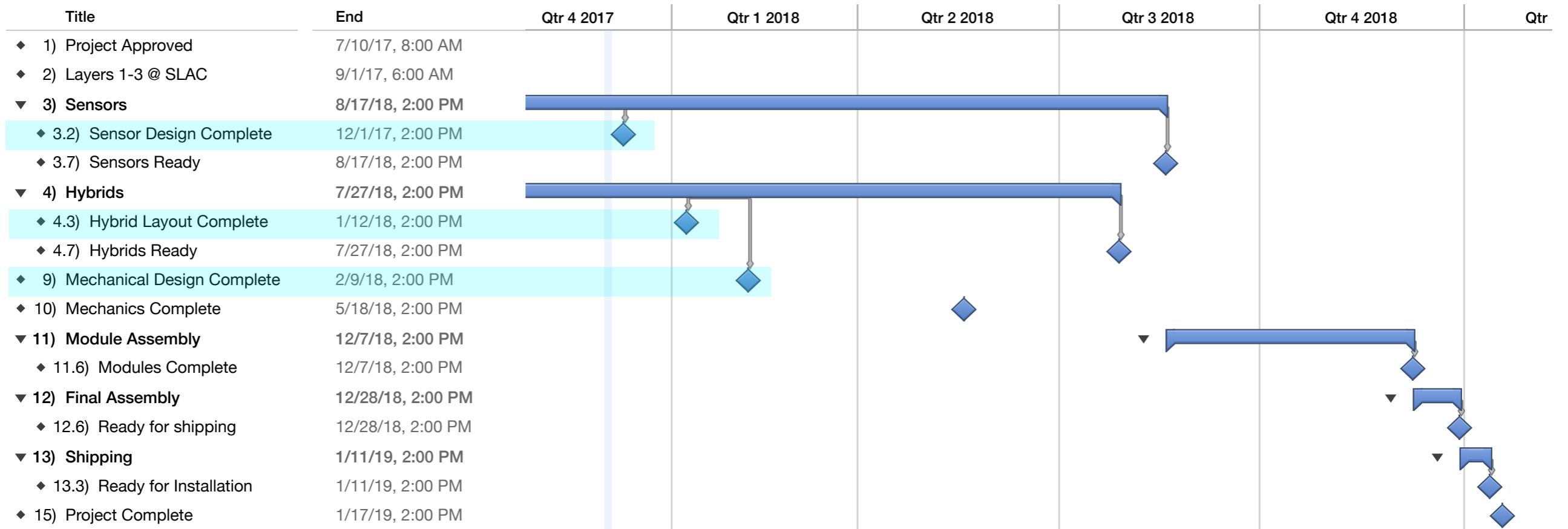
*new hybrids*

*+ assembly and testing*

*new mechanics*

- module supports
- lever blocks
- shims for L2 and L3

# Schedule



*Will internally review the design of three significant components: sensors, hybrids, mechanics*  
*Entire schedule is contingent upon completion of sensor design.*

## **DELIVERY (ORIENTATIVE)**

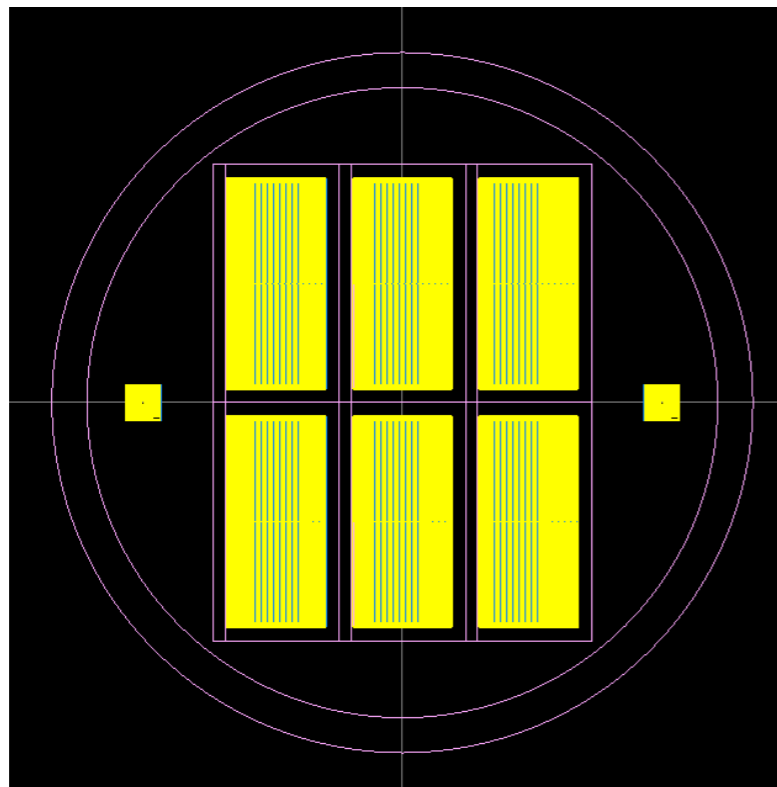
The expected delivery date is 5.5 working months after final layout approval by the client and reception of the masks or after the reception of the substrate 200 um thick wafers (whatever occurs the latest) and the reception of the first payment.

# Sensor Design Status

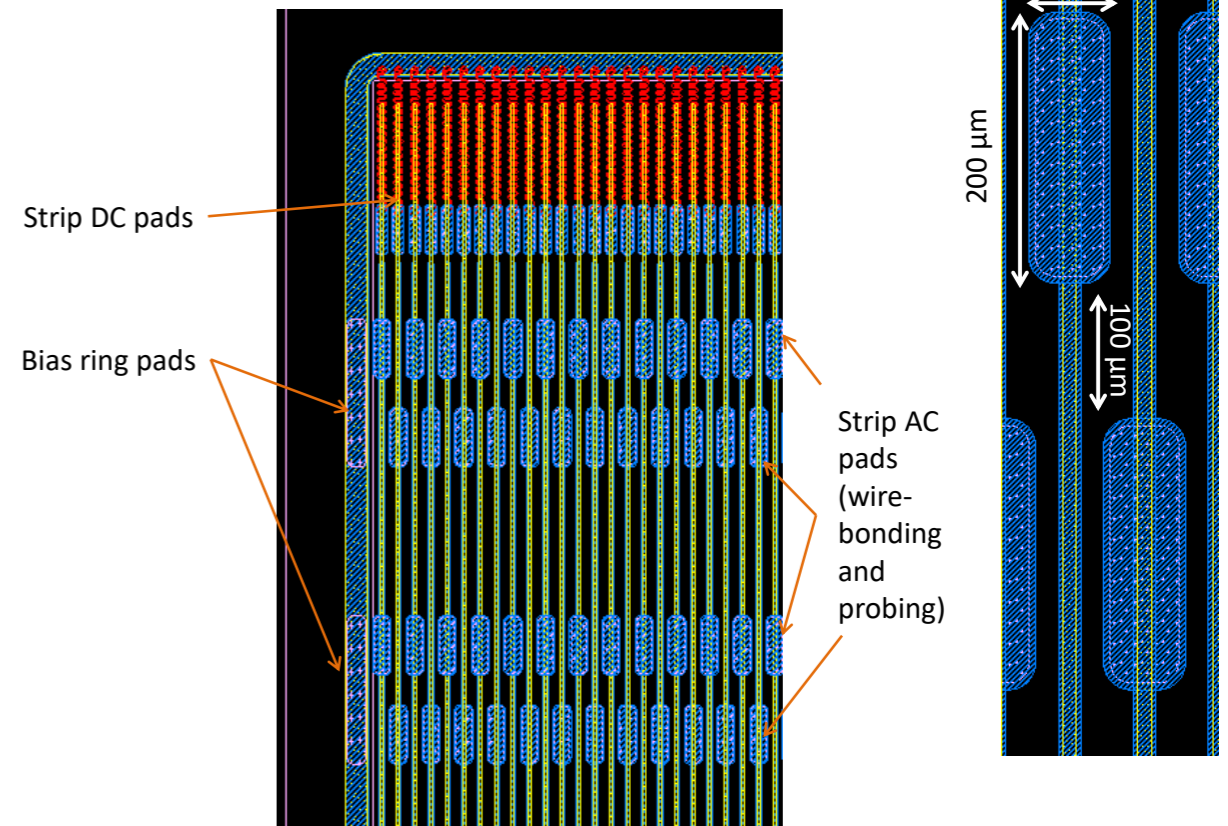
Preliminary design delivered on Oct. 26

Discussion of key details ensued during first week of November.

Updated design proposal sent to Vitaliy on 11/16 and ...I only learned about this last night.



Electrical pads



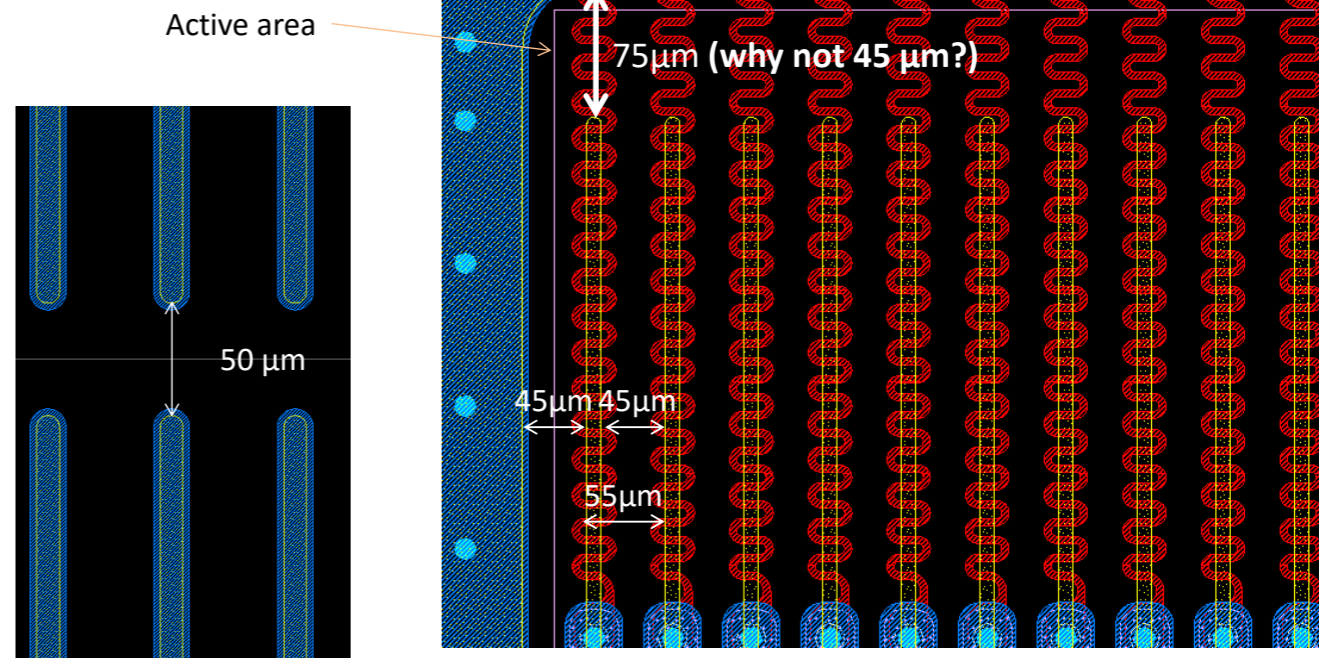
Active area

Active area 14025 x 30000 μm<sup>2</sup>

Width = 255 strips x 55 μm (pitch) = 14025 μm

Length = (14900 μm (length of each strip) x 2 + 50 μm (gap between segments)) = 29850 μm

why 30000?

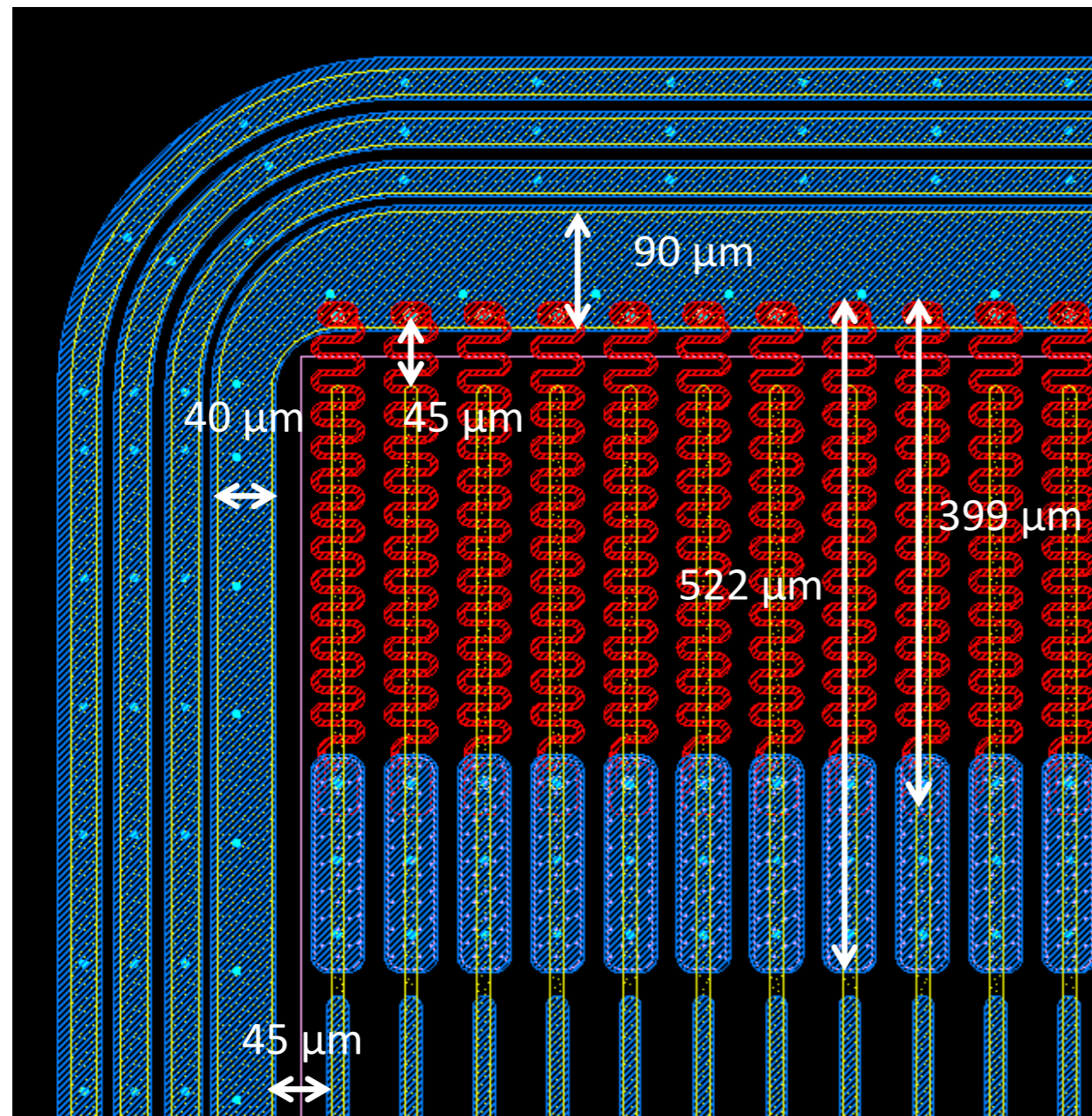




# Final Sensor Design Candidate

## 255 strips, active area and bias ring

- Reduced resistance length = 399  $\mu\text{m}$  (522  $\mu\text{m}$  with DC metal pad).
- Strip length 14952  $\mu\text{m}$  to have the same distance between the strips and the bias ring everywhere.
- Asymmetric bias ring = 40  $\mu\text{m}$  in the slim edge side, 90  $\mu\text{m}$  in the other sides.

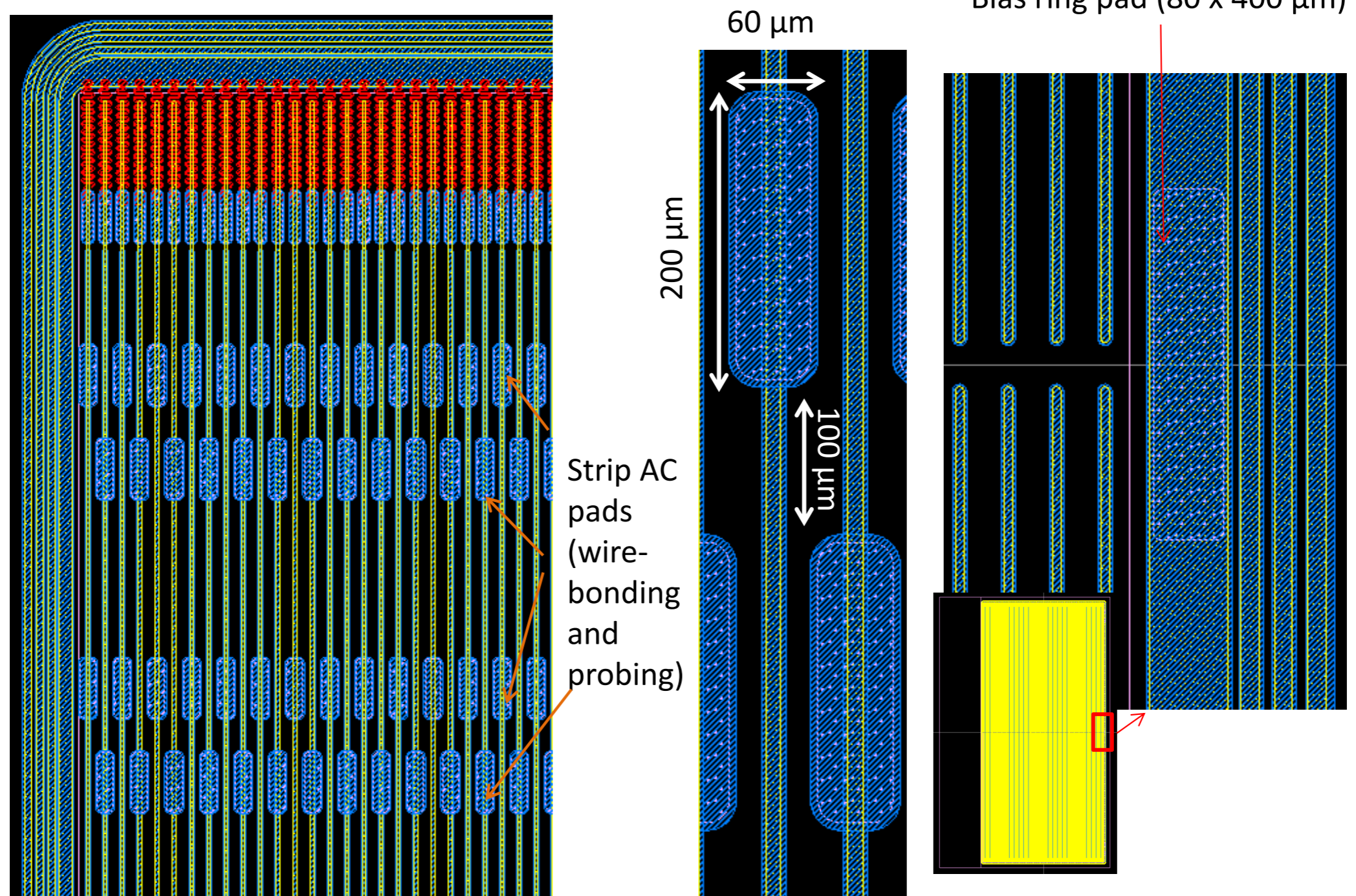


DC pad 170 x 40  $\mu\text{m}^2$



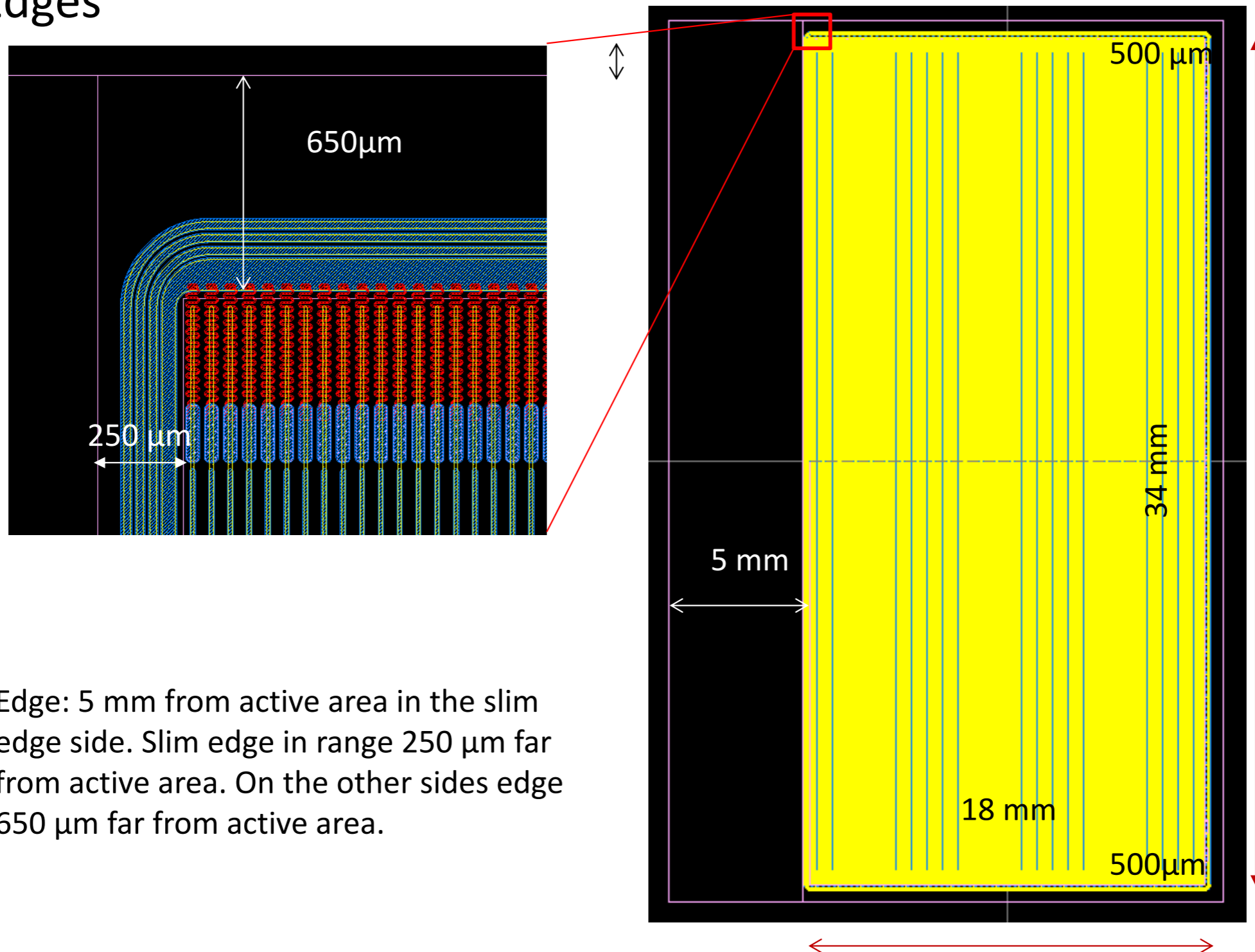
# Final Sensor Design Candidate

## Electrical pads



# Final Sensor Design Candidate

## Edges



Edge: 5 mm from active area in the slim edge side. Slim edge in range 250 μm far from active area. On the other sides edge 650 μm far from active area.

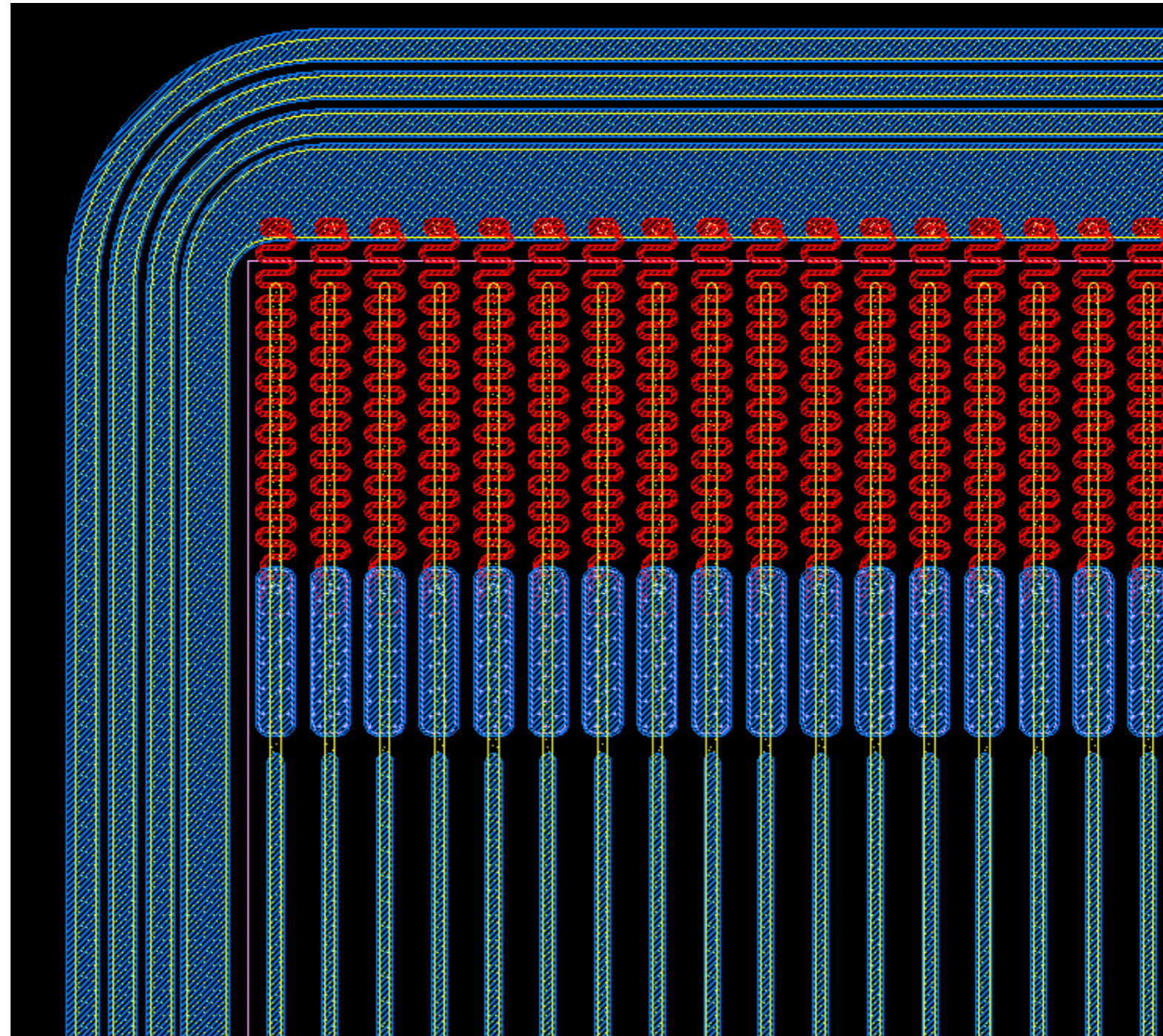


# Final Sensor Design Candidate

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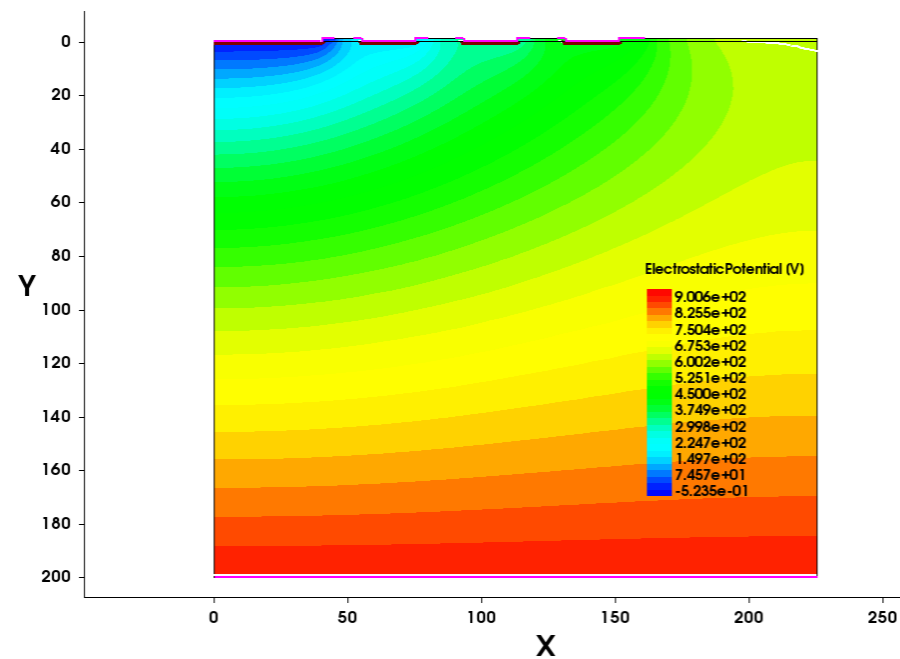
## Guard rings

Three floating guard ring around the bias ring.

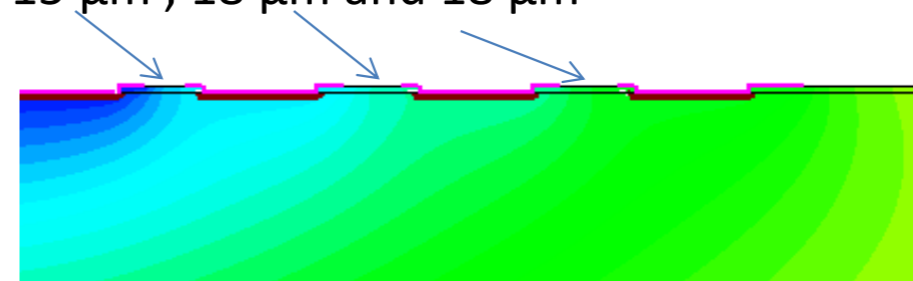




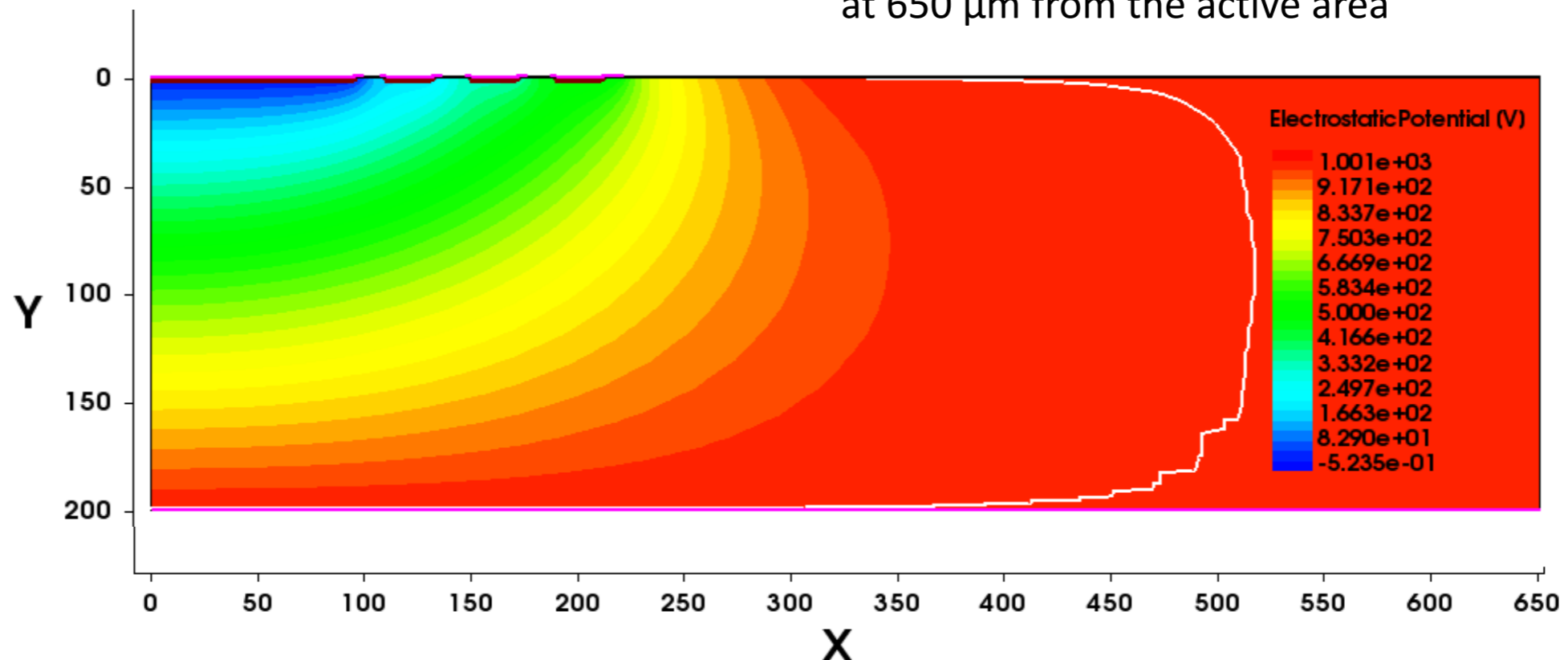
# Final Sensor Design Candidate



Three guard rings 20  $\mu\text{m}$  wide at distance 15  $\mu\text{m}$ , 18  $\mu\text{m}$  and 18  $\mu\text{m}$

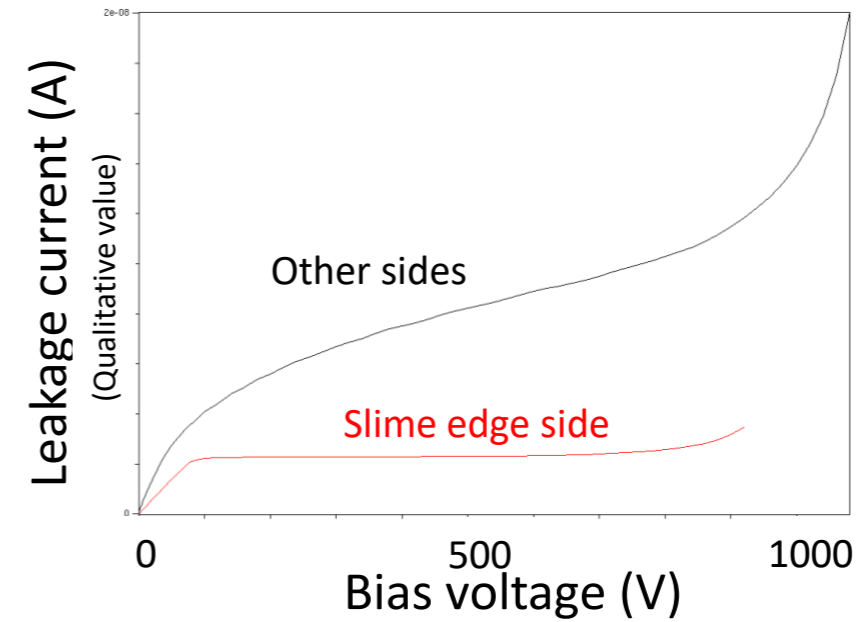
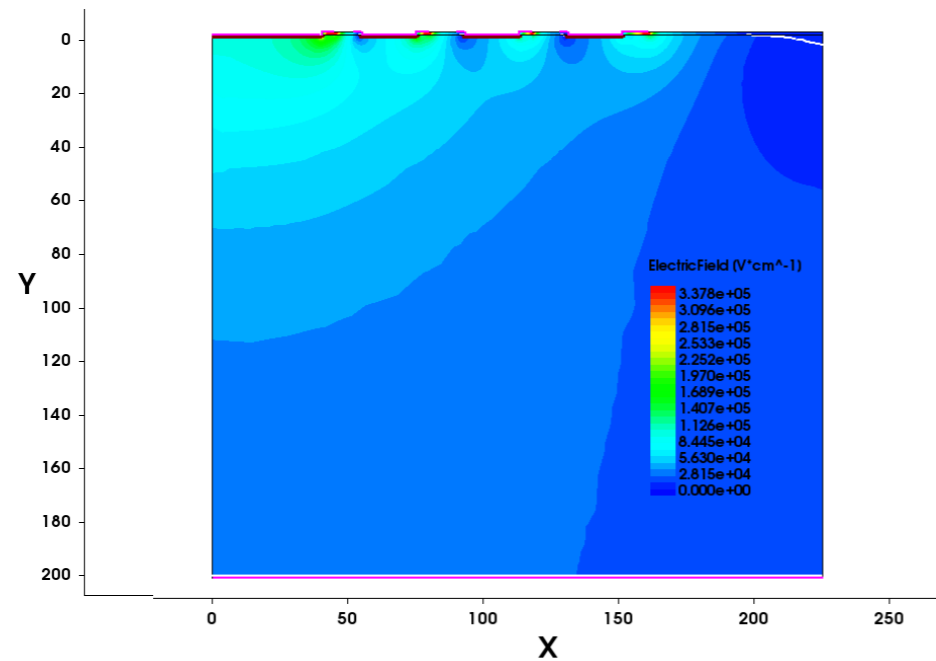


- Slime edge side: bias ring 40 $\mu\text{m}$  wide, cleaving at 250  $\mu\text{m}$  from the active area
- Other sides: bias ring 90 $\mu\text{m}$  wide, saw cut at 650  $\mu\text{m}$  from the active area

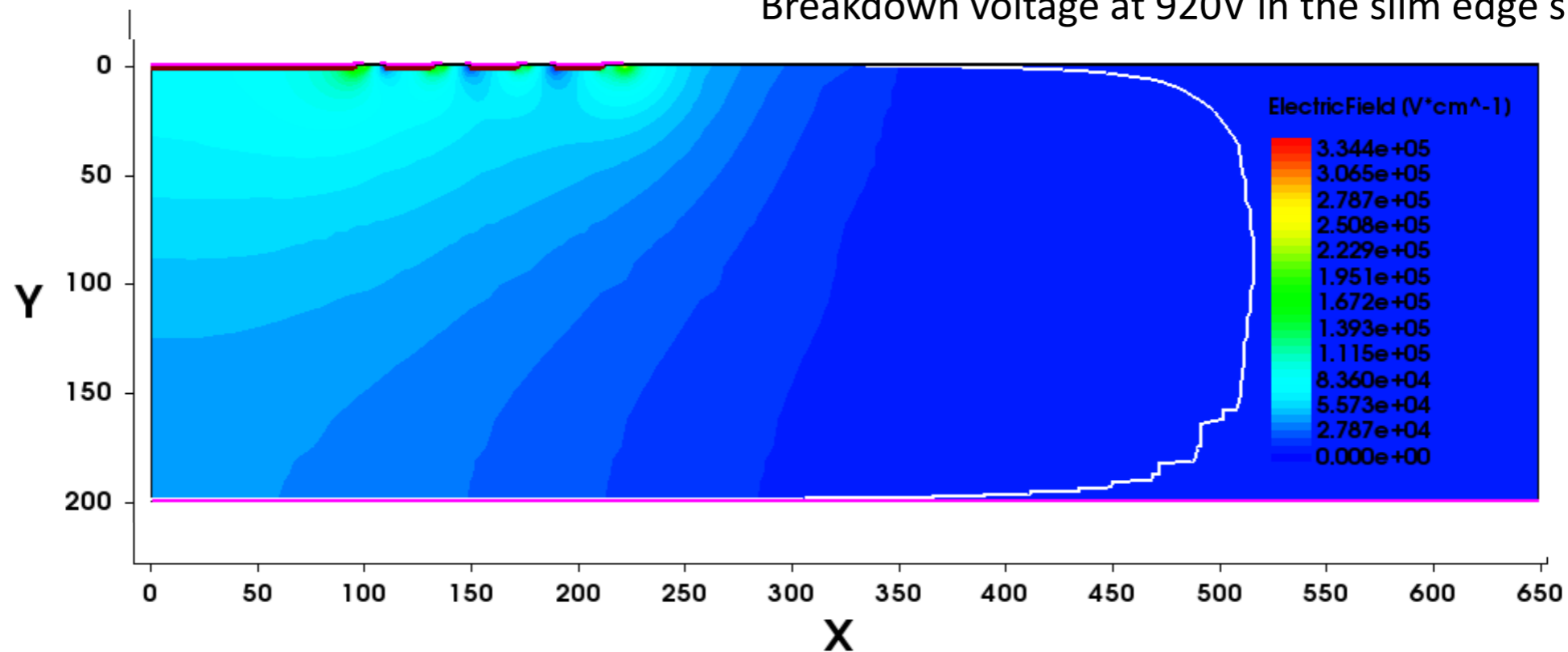


# Final Sensor Design Candidate

\*Value depends on carrier life time and real dimension of the device



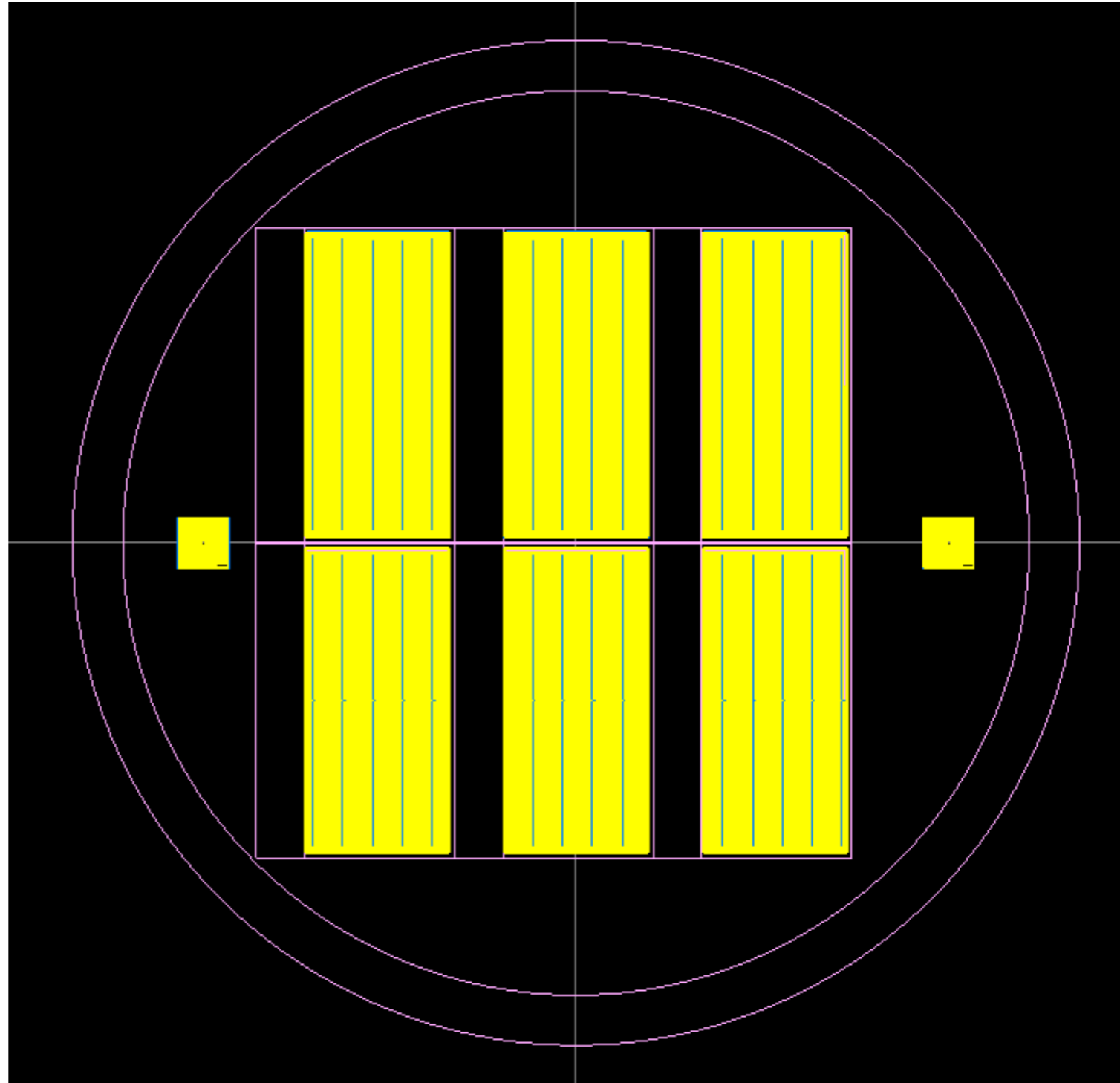
Breakdown voltage at 920V in the slim edge side



# Final Sensor Design Candidate

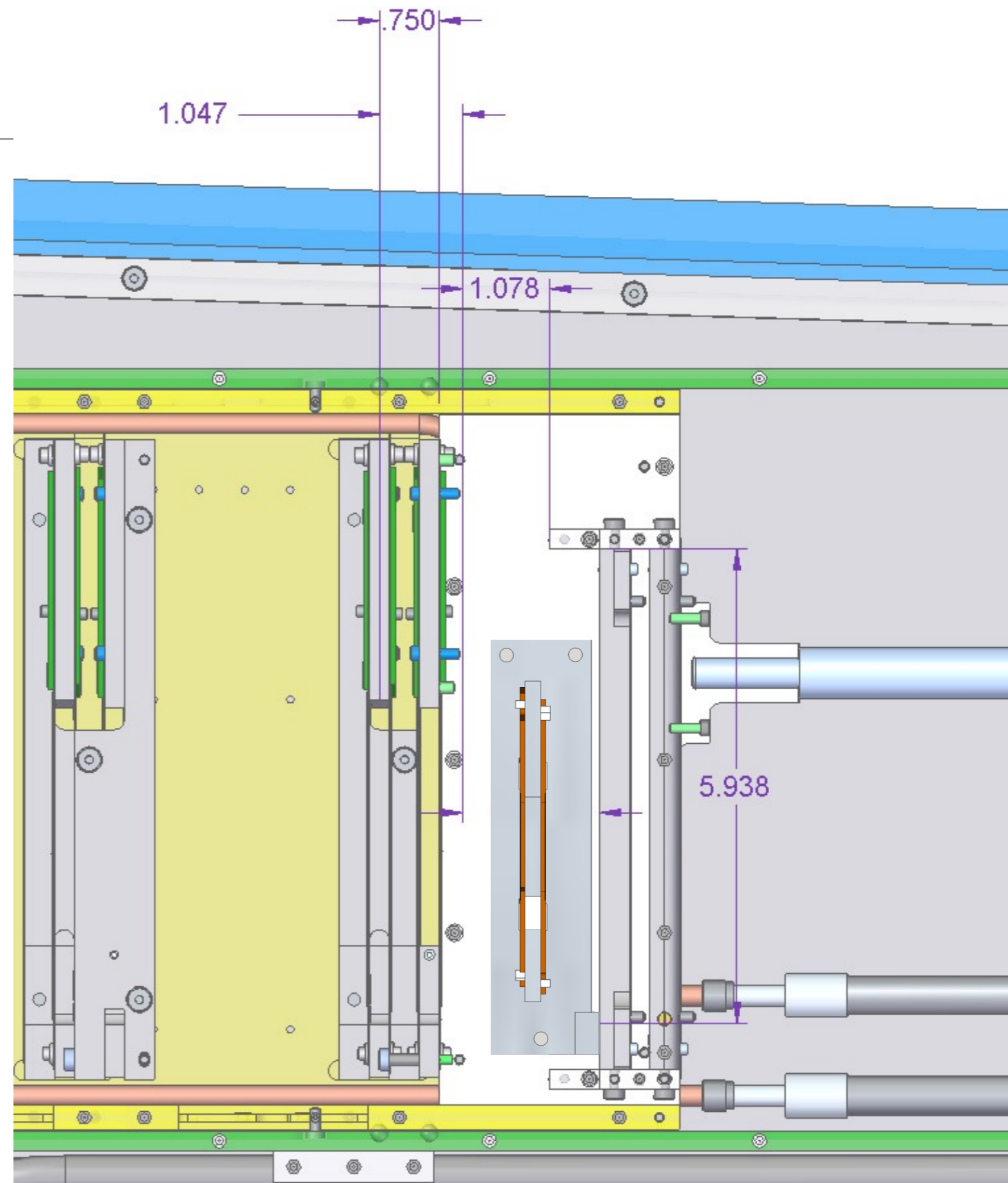
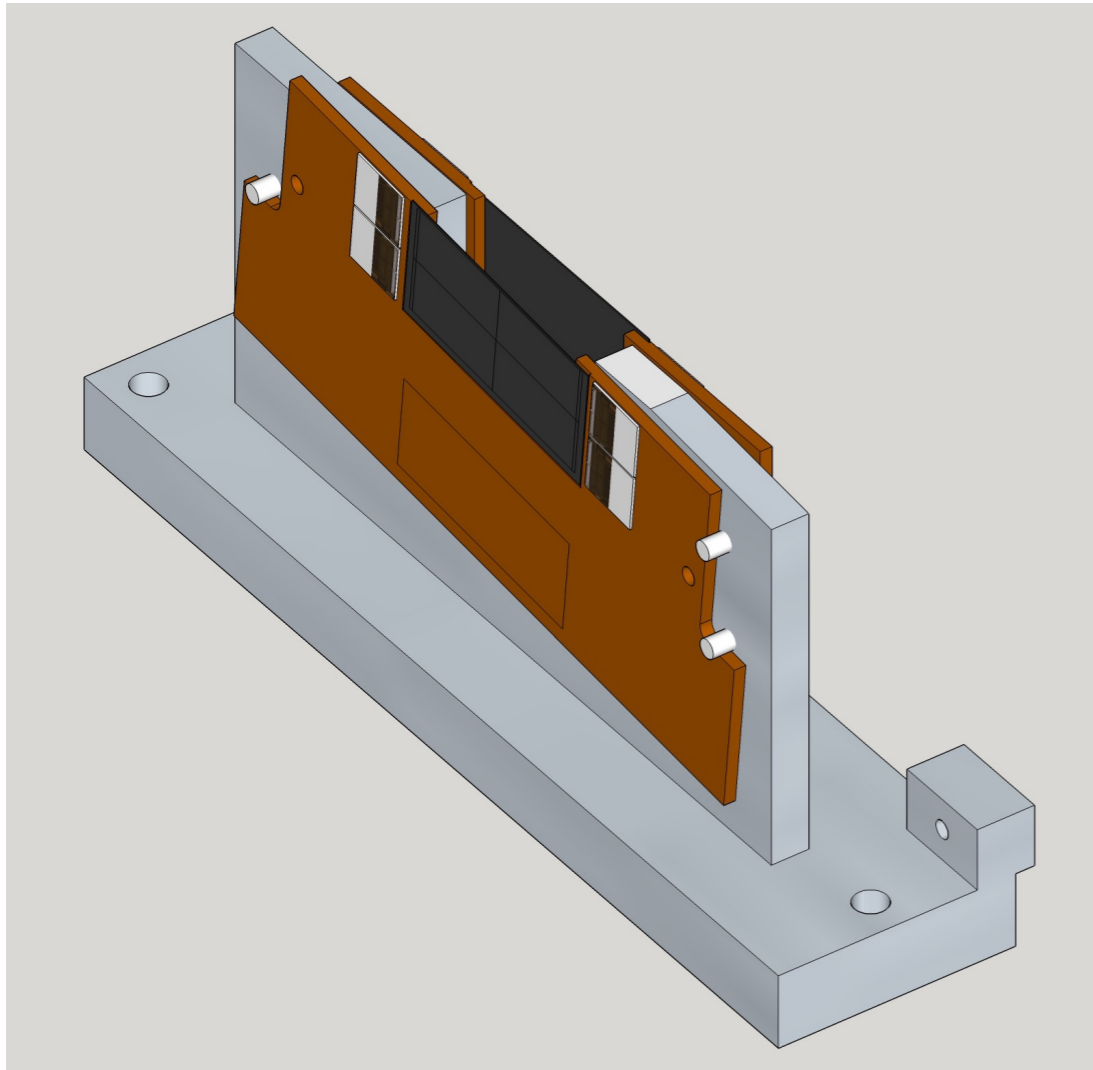
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Six devices in each wafer





# Hybrid and Mechanics



Ready for layout and detailed dimensioning/tolerancing once final sensor design is in hand.

# Summary and Outlook

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- Focus is on critical path - sensor design - where we are late despite steady progress.
- We have completed other tasks, where details depend on sensor design, as much as possible without risking wasted effort
- I will apprise the EC when there is a completed sensor design and the results of the design review.
- Next milestones, hybrid and mechanical designs, are 4 and 8 working weeks respectively after sensor design completion. It makes sense to check back in on these timescales.